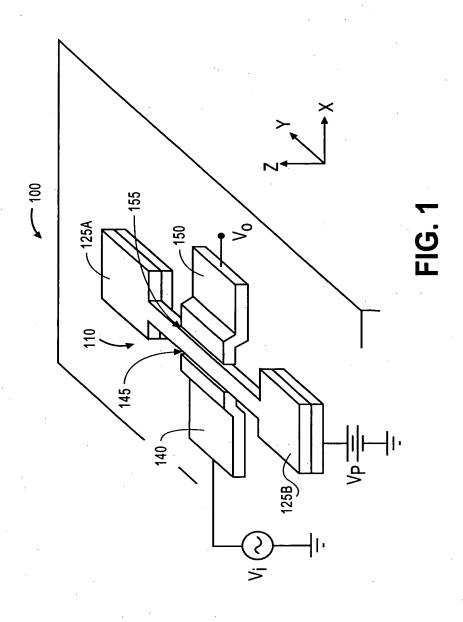
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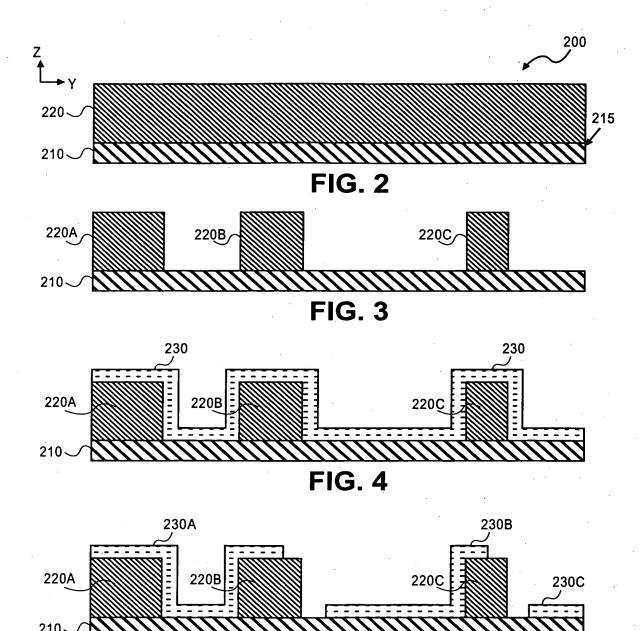
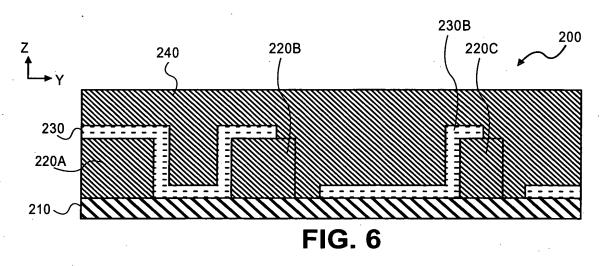


FIG. 5

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230B 230A 240A 240B 240C 220C 220B FIG. 7

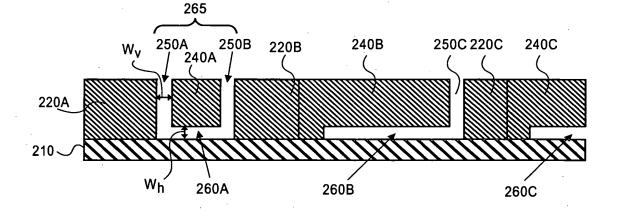


FIG. 8

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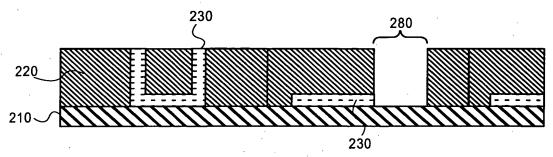


FIG. 9

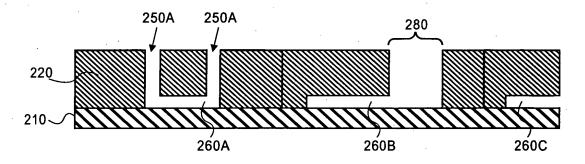


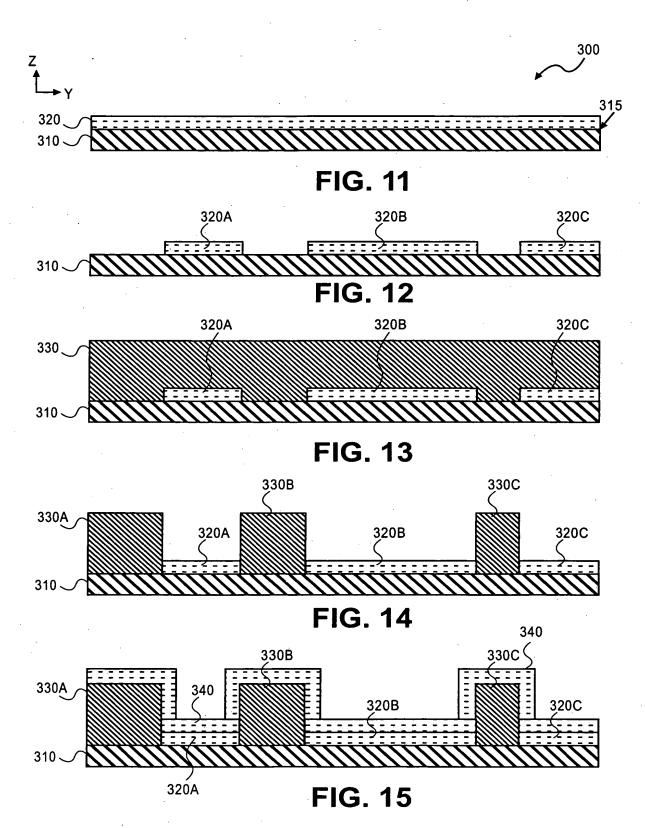
FIG. 10

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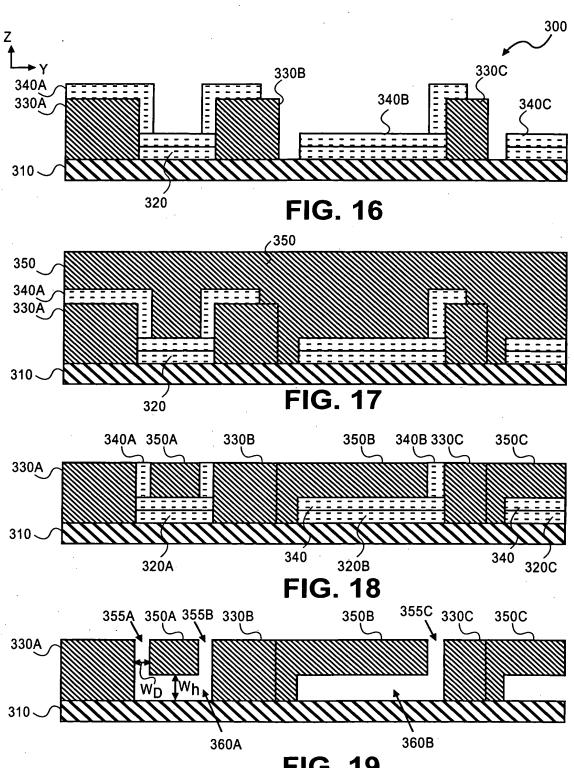
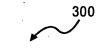


FIG. 19

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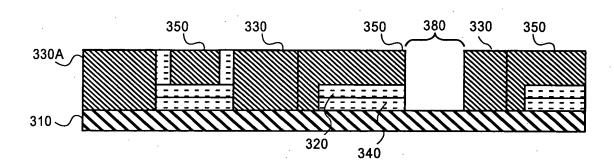


FIG. 20

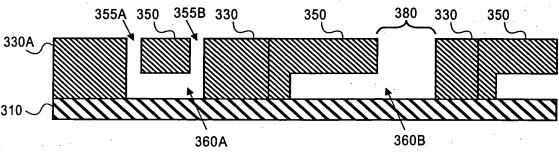


FIG. 21

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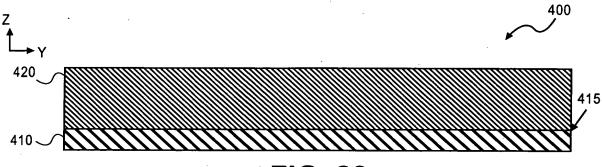
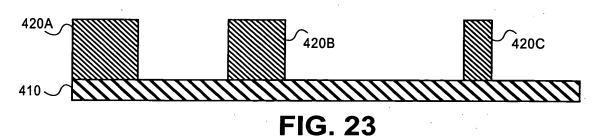


FIG. 22



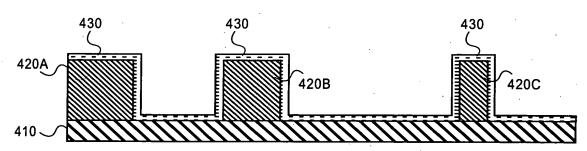


FIG. 24

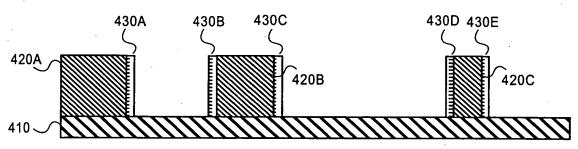


FIG. 25

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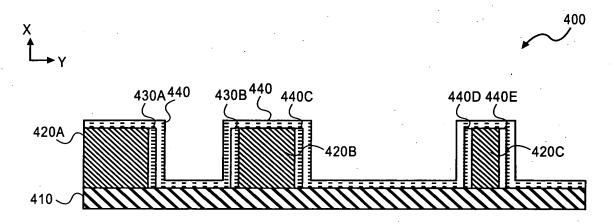
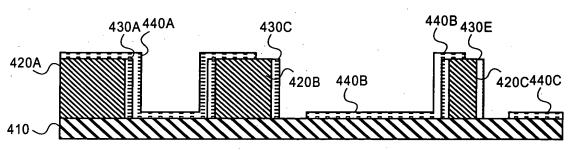


FIG. 26



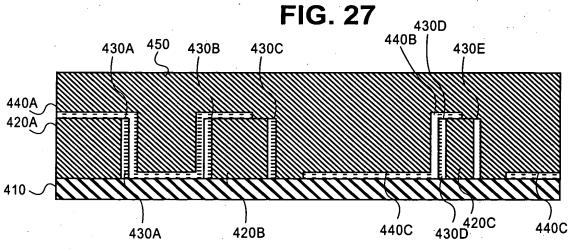
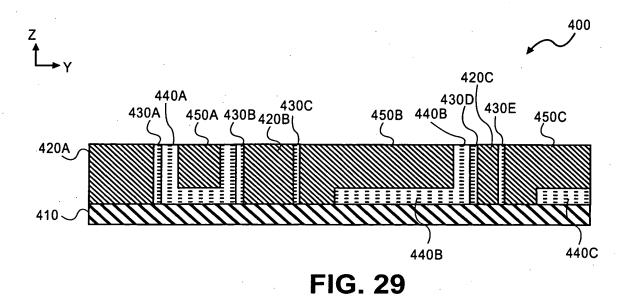


FIG. 28

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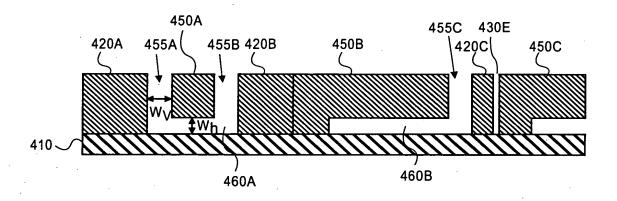


FIG. 30

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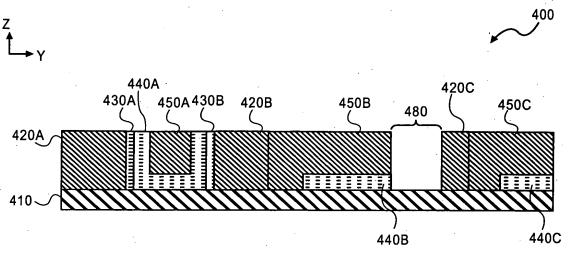


FIG. 31

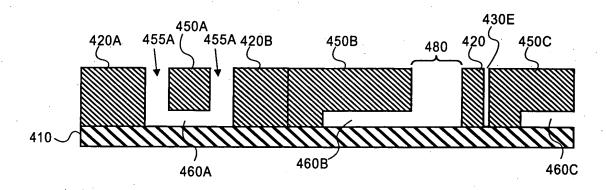


FIG. 32